

Docket No: 740756-1614

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inter Application of)

Takeshi FUKUNAGA et al.)

Application Serial No.: 08/781,920)

Filed: December 30, 1996)

For: METHOD OF FABRICATING A)

SEMICONDUCTOR DEVICE UTILIZING)

A CATALYST MATERIAL SOLUTION)


Group Art Unit: 1762

Examiner: M. PADGETT

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Deborah Tsepel

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AMENDMENT

Commissioner for Patents
Washington, D. C. 20231

Sir:

Responsive to the Office Action of **June 25, 2000**, the period for response having been extended three (3) months until December 25, 2001 (Federal Holiday), the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend claims 24, 31, 32, 40, 41, 49, 50, 55, 56, 59-63 and 66-70 and add new claims 76-92 as follows. For the convenience of the examiner, attached hereto is a marked-up copy of the claims as amended.

24. (Amended) A method of fabricating a semiconductor device comprising steps of: